

## **EUCALL - WP6 – HIREP**

Milestone 6.2: M4 / 31.01.2016

## "List of sample types for identification software"

The identification software to be developed in the work package HIREP and delivered as D6.7 at the end of 08/2018 has to cover the identification and precise position measurement of at least the following types of samples:

- 1. Periodically placed or manufactured targets on a support / substrate of equal or similar shape. The software has to find the position of the geometrical center of the targets with respect to the reference marks of the frame / substrate. Position information from the placement / manufacturing process can be used for a rough approach.
  - a. foils placed in a sandwiched holder with holes / windows
  - b. flat cones of tens of µm tip and hundreds of µm base (lithography)
  - c. micro dots with a size from 1 µm to several tens of µm
  - d. reduced mass and nanostructured targets
  - e. micrometer sized biological samples positioned by pick-and-place
  - f. wires spanned across micrometer sized holes / windows
- Statistically distributed targets on a support / substrate. The software has to find the position of the geometrical center of the targets with respect to the reference marks of the frame / substrate. The complete substrate area has to be screen

the reference marks of the frame / substrate. The complete substrate area has to be screened and analyzed.

- a. dried out suspension with sphere shaped single particles or clusters of them
- b. self-organized growth of metallic / semiconductor / insulator micro structures
- c. solid foams of two chemical components with open surface / pores
- d. crossing points inside of ravels of filament like materials (nano / micro wires / fibers)
- Homogenous materials with defects / cracks / discontinuities. The software has to find the position of the imperfections with respect to the reference marks of the frame / substrate. The target list will be a periodic grid with omissions at the erroneous locations.
  - a. metallic glasses like GeO<sub>2</sub>, SiO<sub>2</sub>(80%)+Na<sub>2</sub>O<sub>2</sub>(20%)
  - b. thin films of metal / semiconductor / insulator materials on metal / semiconductor / insulator substrates
  - c. thin films of metal / semiconductor / insulator materials structured with metal / semiconductor / insulator nano and micro structures

This list will be continued /actualized during the time span of the project and the development of the sample identification software.

